



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	Hou, Chien-Chou; et al.	)	Examiner:	Deo, Duy Vu Nguyen
		)		
Serial No.:	10/600,377	)	Art Unit:	1765
		)		
Filed:	June 20, 2003	)	Our Ref:	B-5130 621033-6
		)		
For:	"METHOD OF ETCHING UNIFORM SILICON LAYER"	)	Date:	September 22, 2006
		)		
		)	Re:	<i>Amendment and Response</i>
		)		

AMENDMENT AND RESPONSE

Mail Stop RCE  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

This is in reply to the Advisory Action mailed on September 8, 2006, and in reply to the final Office Action mailed on June 23, 2006, a response to which is due no later than September 23, 2006.

The Applicants submit this amendment pursuant to 37 C.F.R. 1.114 together with a Request for Continued Examination. Please amend the above-identified application as described below and consider the following remarks. **All amendments and remarks herein are made without prejudice.**

A Request for Continued Examination (RCE), a fee form, and requisite fee are included with this response. A paper showing the calculation of excess claims fees and a check for the requisite fee are also enclosed.

**Amendments to the Claims** are reflected in the listing of claims that begins on page 2 of this paper.

**Remarks/Arguments** begin on page 6 of this paper.